



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
BEFORE THE BOARD OF APPEALS

In Re Application of:)
Inventors: Apostolos Voutsas)
Serial No.: 09/893,866) Attorney docket No.:
Filed: June 28, 2001) SLA592
Title: METHOD FOR FORMING) Group Art: 5636
SILICON FILMS WITH TRACE)
IMPURITIES) Examiner: A. Sarkar

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CERTIFICATION UNDER 37 CFR § 1.8

I hereby certify that the documents referred to as enclosed herein are being deposited with the United States Postal Service as first class mail on this date 1/23/2003 in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

Date 1/23/2003 Signature [Signature]

Hon. Commissioner for Patents and Trademarks
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

REPLY BRIEF

This paper is a reply to an Examiner's Answer mailed by Examiner
Asok Sarkar, Group Art 5636, on January 15, 2002.

ARGUMENT AND DISCUSSION

The Examiner's position, as stated in the Examiner's Answer, appears to be that the Applicant is attempting to claim a pioneering use of impurities in a silicon target used for sputtering. However, this is not what the claims actually recite. The Applicant's claims describe a relationship between the concentration of impurities in the target and a concentration of the impurities in the resultant film. None of the prior art references teach a relationship between the concentration of impurities in the target and in the resultant film. The Applicant's position is best summarized in the Appeal Brief on page 6, beginning at line 5.

Respectfully submitted,



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Date: 1/23/2003

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